



JIPELEC™ RTP

Leading supplier of Rapid Thermal Processing Equipment to the Semiconductor, PV and MEMS Industries

ACADEMIC RESEARCH

JETLIGHT™



Batch-type RTA/RTP furnace
Atmospheric or vacuum thermal treatment
10 wafers per batch (2-inch circular max.)
Gas introduction capability
Manual loading through quartz tray
Cost-effective & versatile

PROCESS DEVELOPMENT

JETFIRST™



Single-wafer RTA/RTP furnace
Atmospheric or vacuum thermal treatment
From pieces of samples to 300-mm wafer
Gas introduction capability
Manual loading through lid
Ideal for process engineering and qualification

PRODUCTION

JETSTAR™



Single-wafer RTA/RTP furnace
Atmospheric or vacuum thermal treatment
From pieces of samples to 300-mm wafer
Gas introduction capability
Manual or automated loading
Research-to-production equipment